

*Greetings from  
Georgia Tech*

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## **3D Systems Packaging Research Center**

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*John Pippin Chair in Microsystems Packaging & Electromagnetics*

*School of Electrical & Computer Engg.*

*School of Materials Science & Engg.*

*Director, 3D Systems Packaging Research Center (PRC)*



# Outline



- ❑ PRC – An Overview
- ❑ Heterogeneous Integration
- ❑ Glass Interposer Technology
- ❑ Glass Interposers for Space Applications
- ❑ Summary

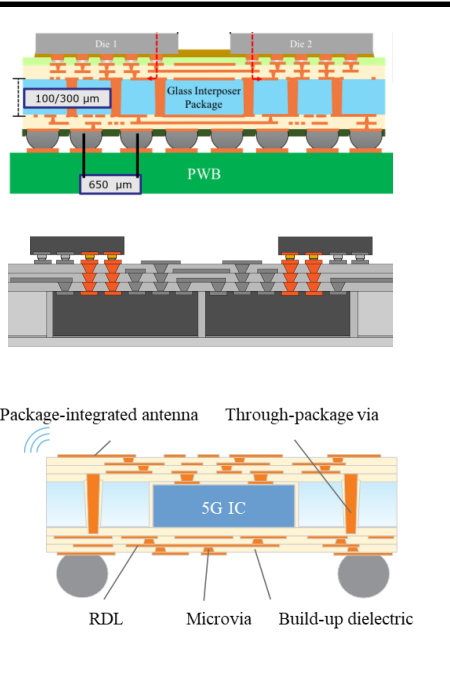




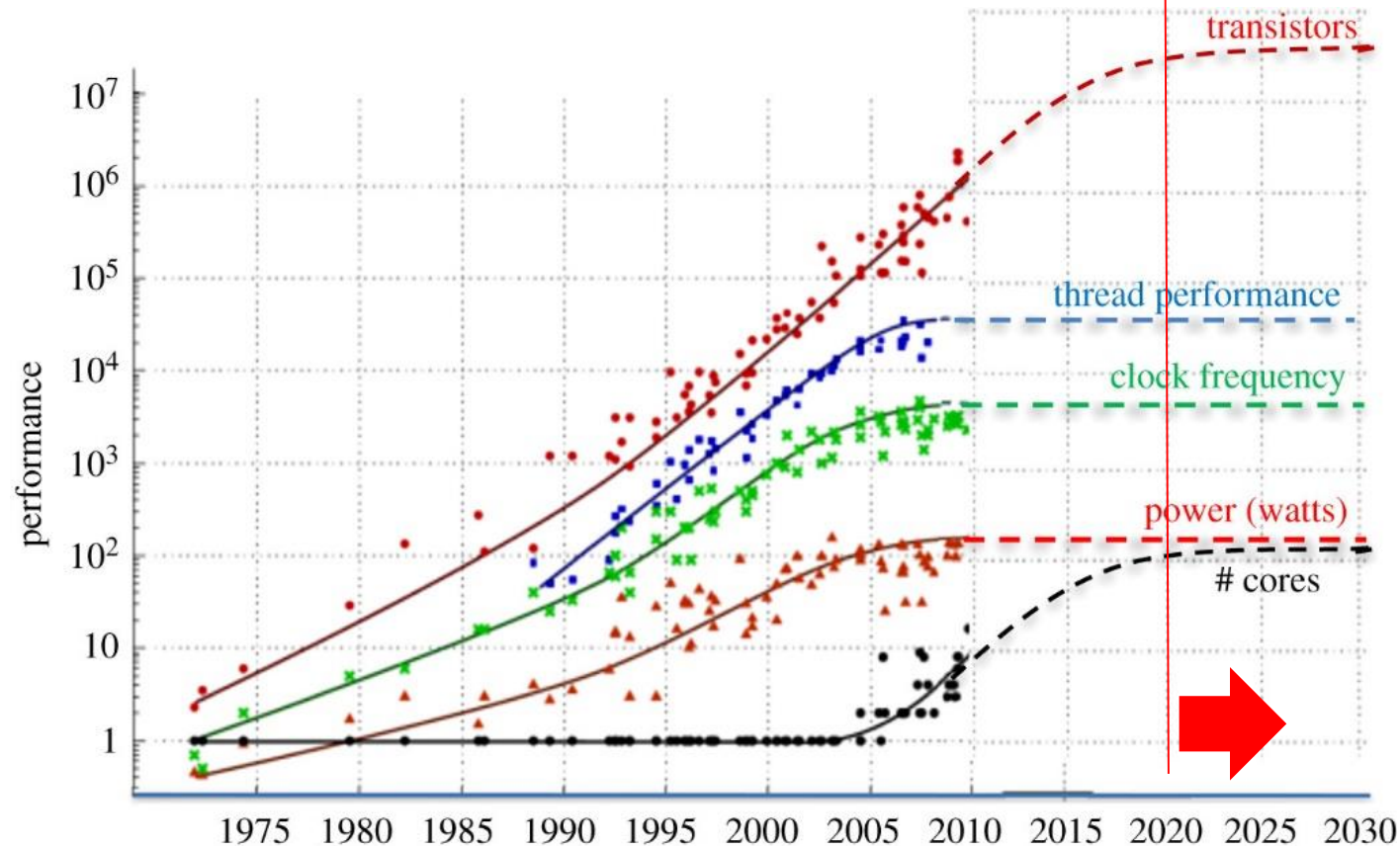
# Packaging Research Center (PRC)

Graduated NSF Engineering Research Center  
26 Faculty (ECE, MSE, ChE, ME)  
11 Staff (Research & Admin)  
40+ G Students (+ UG)  
33 Collaborators (Industry/Govt. Labs)  
3 Visiting Engineers on Campus

Advanced Packaging &  
System Integration



# Future of Computing



Moore's  
Law  
slowing  
down

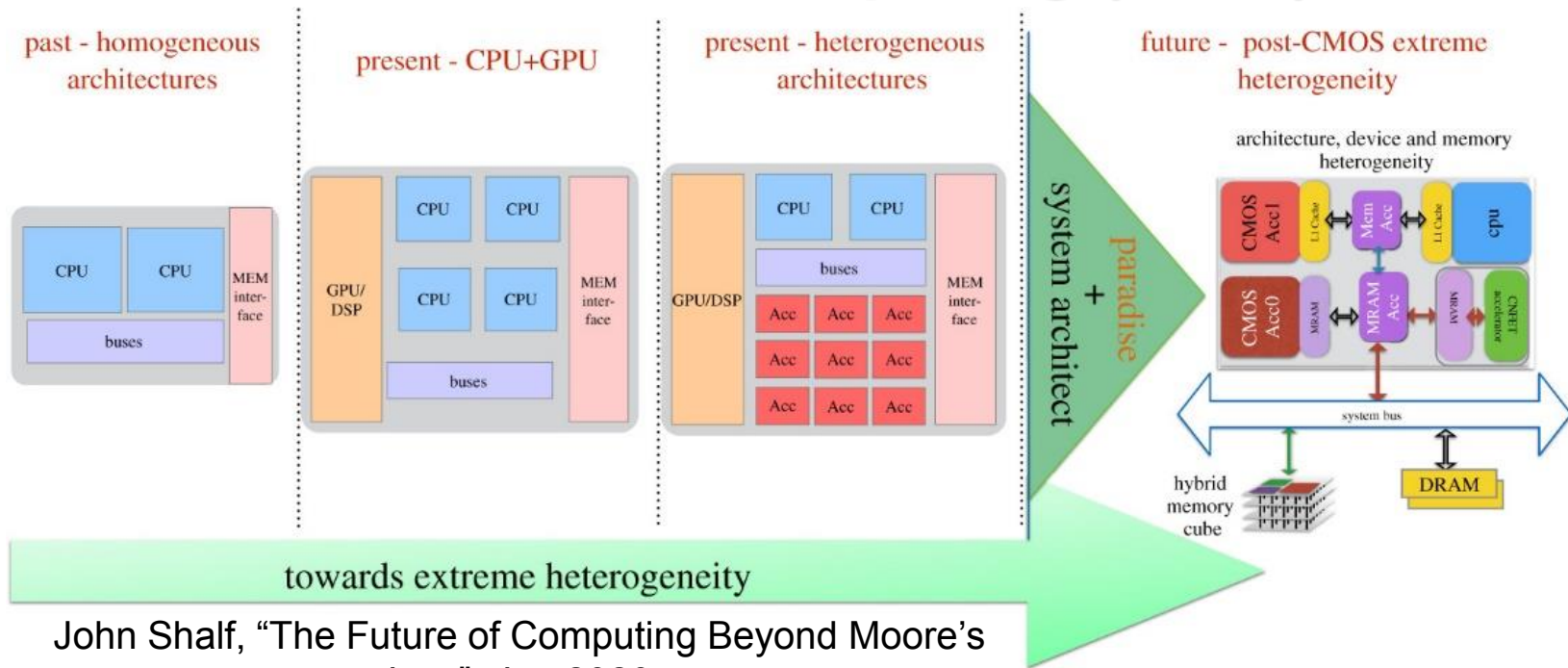
John Shalf, "The Future of Computing Beyond Moore's Law", Jan 2020

<https://doi.org/10.1098/rsta.2019.0061>

## □ Path Forward

- More efficient architectures & advanced packaging (next 10 years)
- New materials & devices (20+ years)
- New models for computation (Future ex: quantum computing)

# Future of Computing (cont.)



## □ Architectural innovations

- Use of Accelerators (chips in-between a CPU & ASIC with IP Reuse)

## □ Extreme Heterogeneity

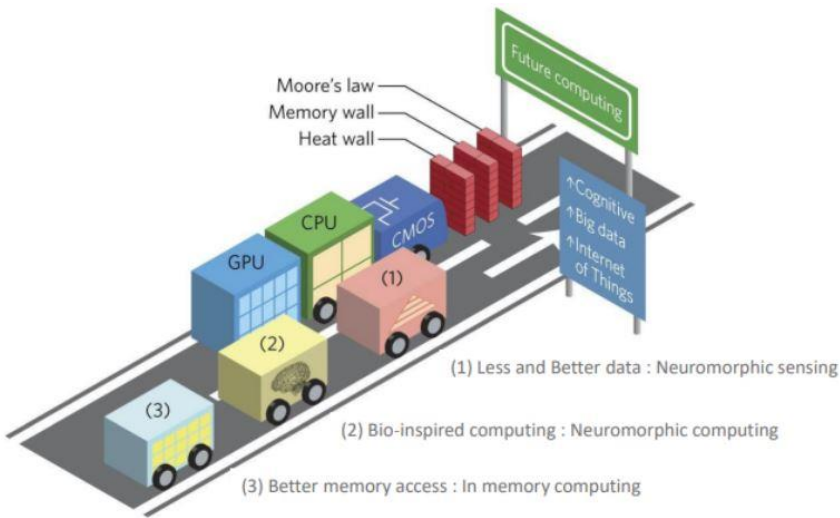
- Smaller Dies from different advanced process nodes to reduce die cost

## □ Data movement

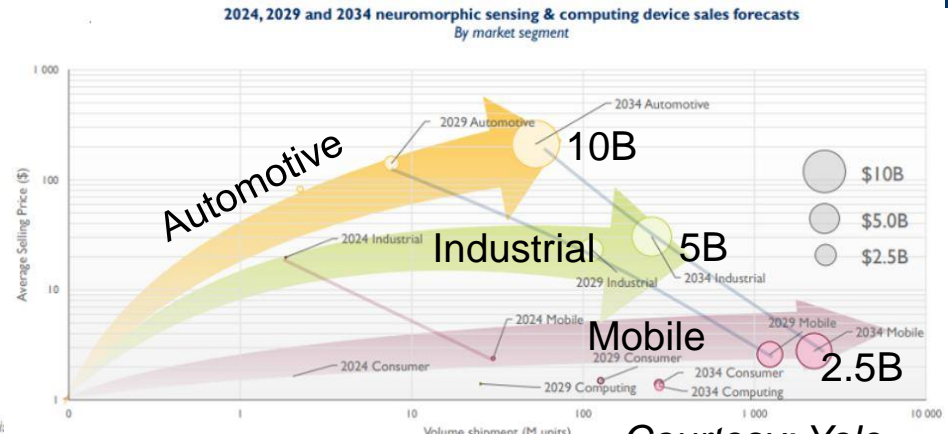
- Low Energy/Bit (EPB) with high Bandwidth density



# Artificial Intelligence

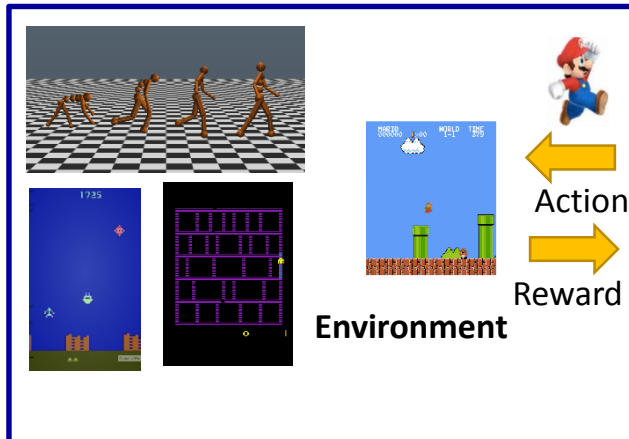


Adapted from "The future of electronics based on memri."  
Mohammed A. Zidan, John Paul Strachan & Wei D. Lu, Nature Electronics 2010



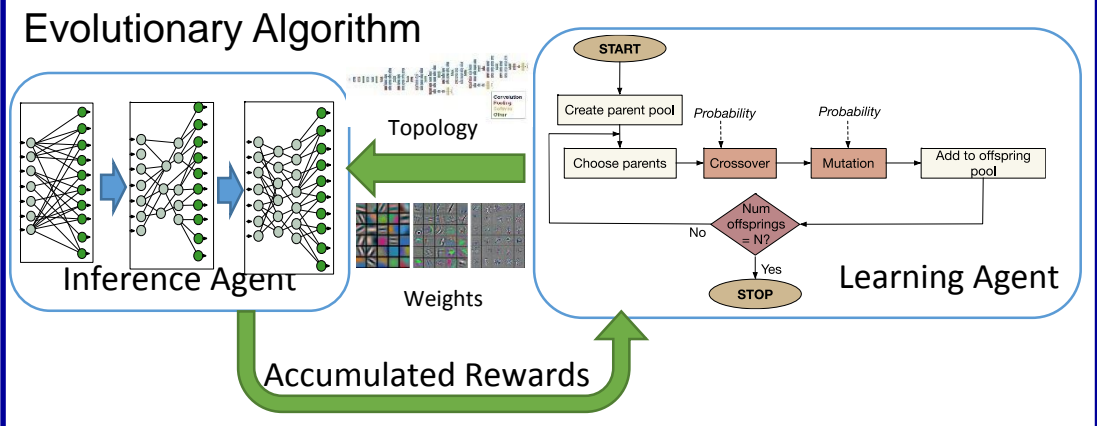
Courtesy: Yole

## Wireless



Data Movement: Long Distances

## Compute



Data Movement: Short Distances

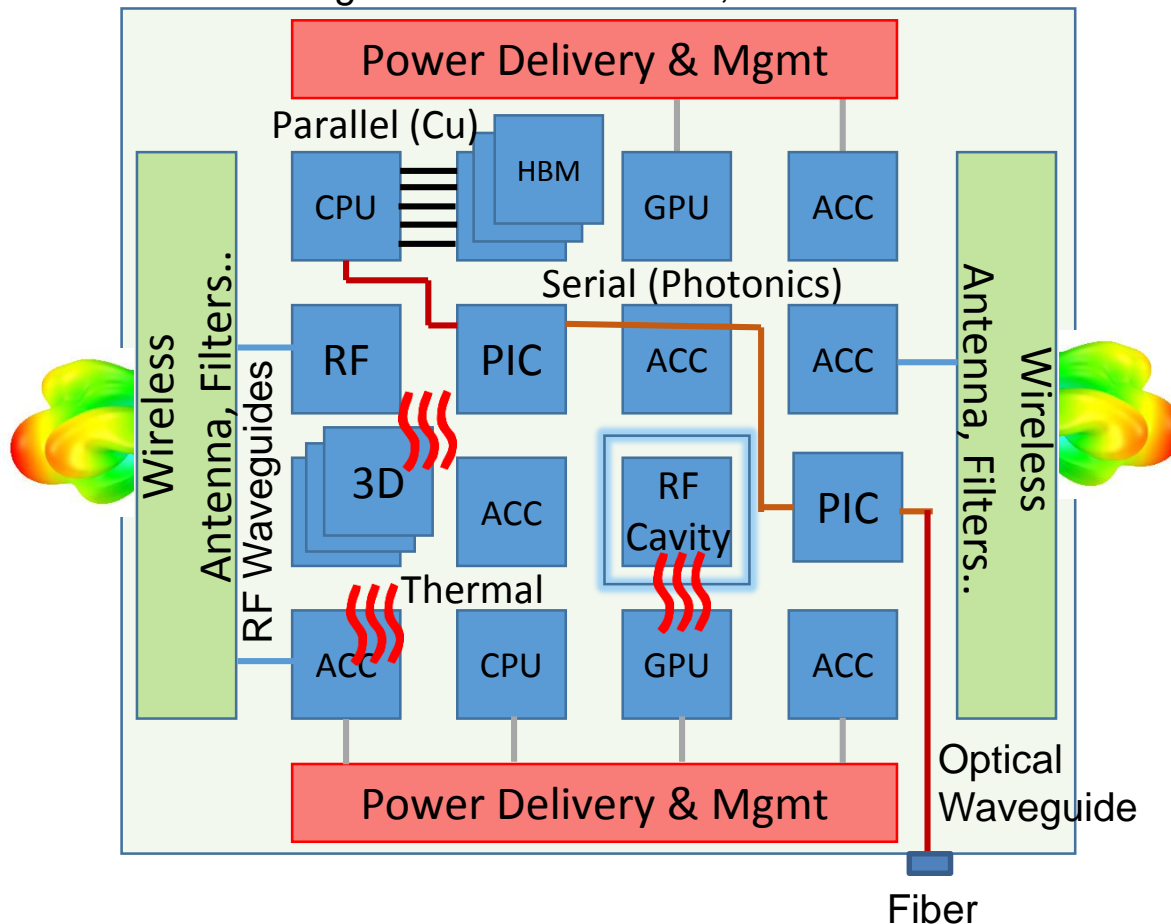
Courtesy: T. Krishna, GT

❑ Challenge: Digital & Wireless Integration on a Single Module

# Heterogeneous Integration

- ❑ Multitude of chips from different process nodes, wafer sizes, foundries & domains

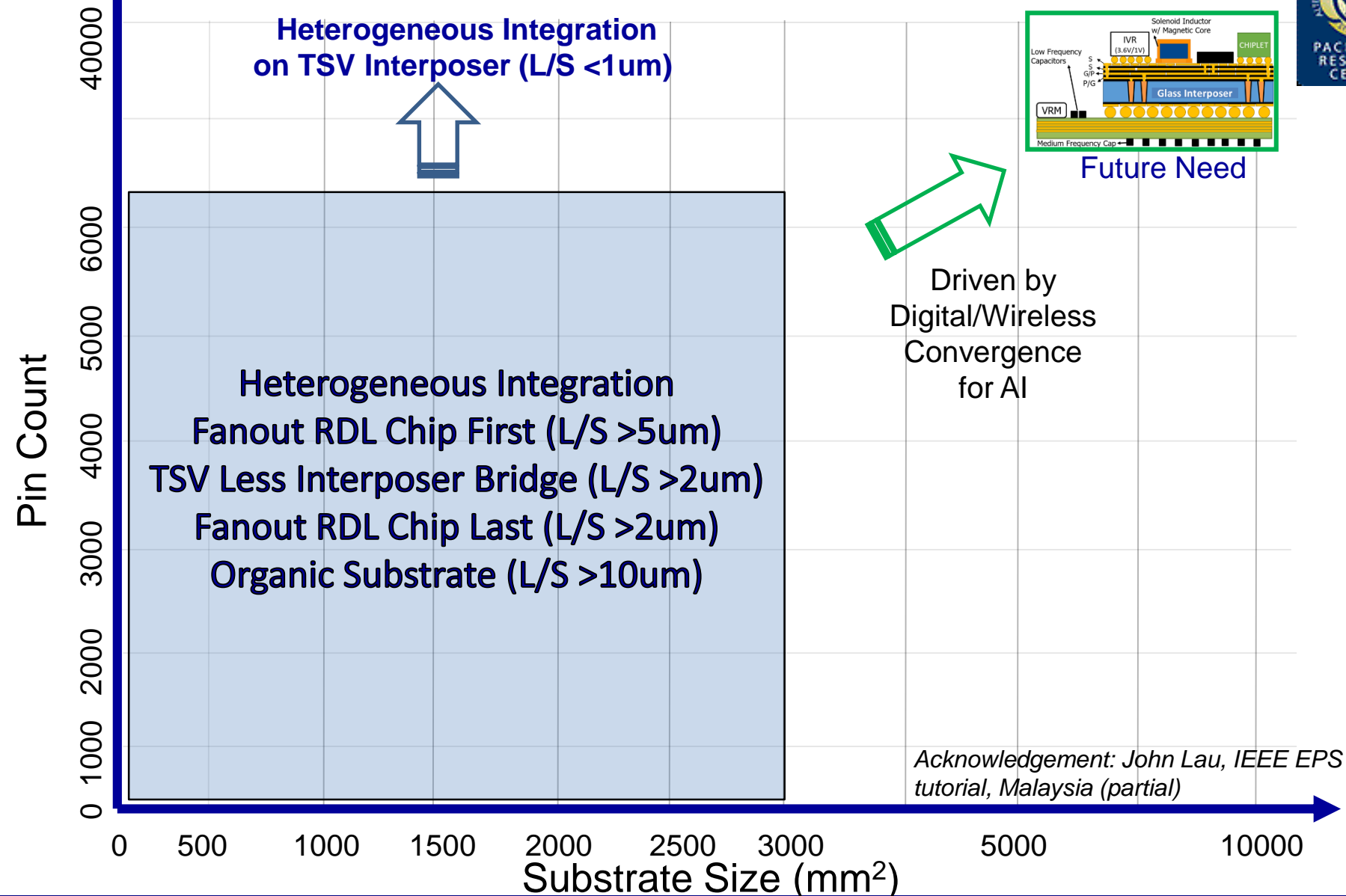
Integrated Substrate:  $>10,000 \text{ mm}^2$



- ❑ Compute
  - Electronics
    - Parallel I/O
    - High BW Density
    - $<3\text{mm}$  length
  - Photonics
    - Serial I/O
    - High BW
    - $>200\text{mm}$  length
- ❑ Wireless
  - Massive MIMO
    - High Data Rate
    - $>20\text{m}$

HETEROGENEOUS INTEGRATION ENABLES CONTINUATION OF MOORE'S LAW

# Substrate Size driven by Artificial Intelligence

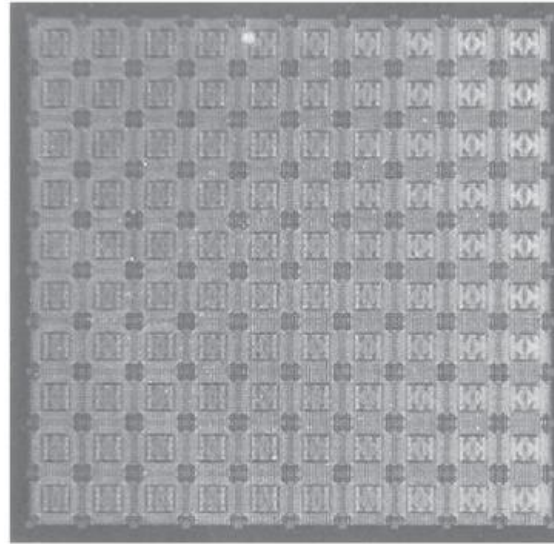




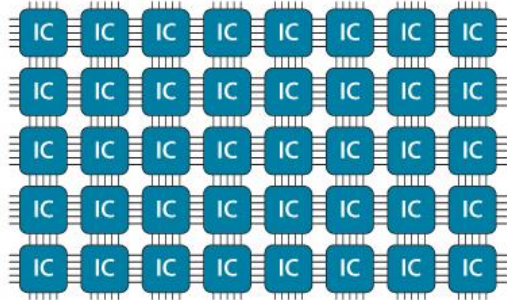
# Technology for Digital/Wireless Convergence



61-Layer LTCC/Cu-MCM  
(IBM, 1992)



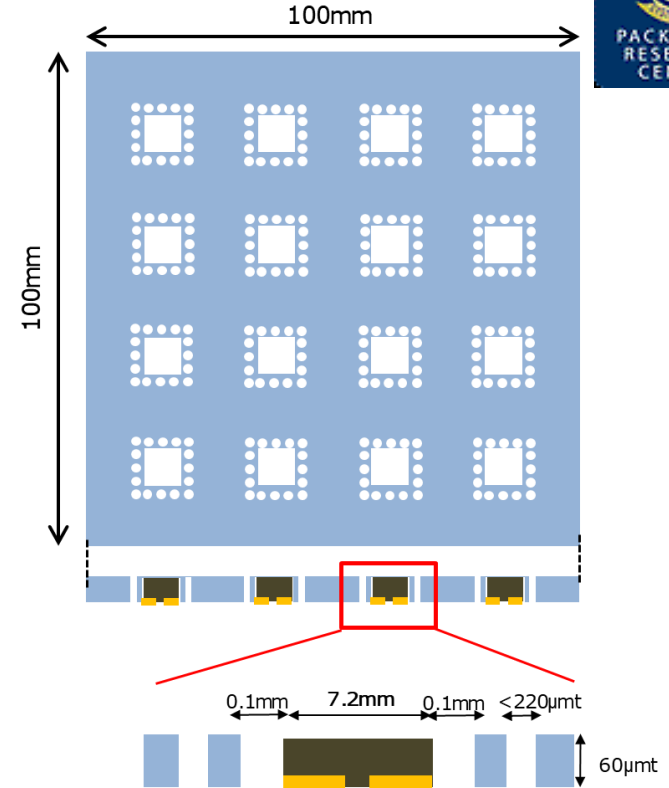
Multi-chip Module (MCM)  
Single CPU



Dense Connectivity  
between ICs

Rao. R. Tummala, McGraw Hill, 2019.

Glass Interposer



## Silicon Interposer

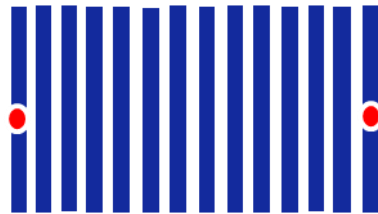
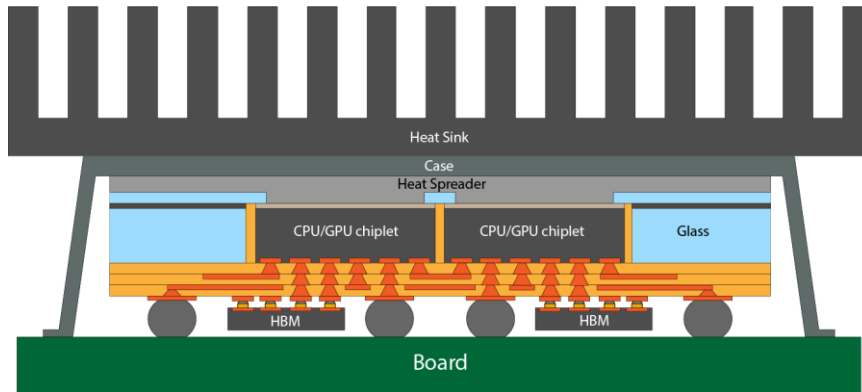
- 100mm size on a wafer too expensive



## Glass Interposer

- 100mm size on a panel cost effective

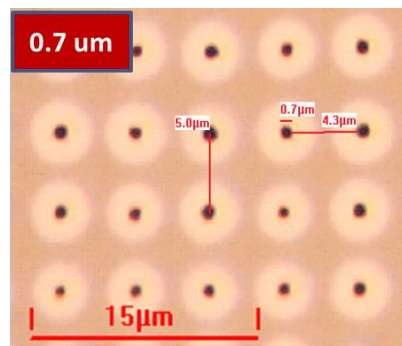
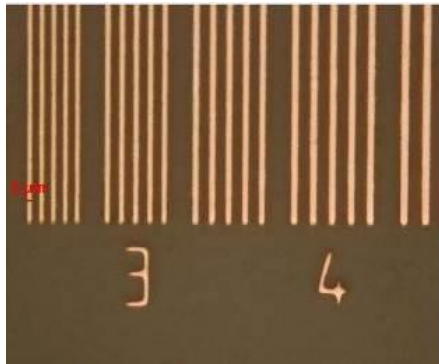
# High Density Connectivity between Chips



L/S/Via = 1/1/1  $\mu\text{m}$

Semi-Additive Process

Microvia

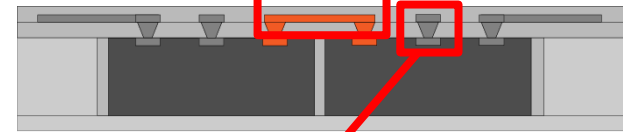


0.7um/5um pitch

Chip First

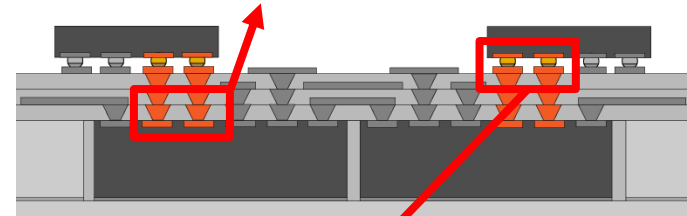
## High-density RDL characterization

- 2-5  $\mu\text{m}$  microstrip lines, 3 different dK
- 2-5  $\mu\text{m}$  L/S coupled MS lines
- 0.25 – 5 mm long lines



## Chip-PKG Microvia characterization

- 3-10  $\mu\text{m}$  via, 7-20  $\mu\text{m}$  pad
- Impact of pad size, via diameter, via pitch

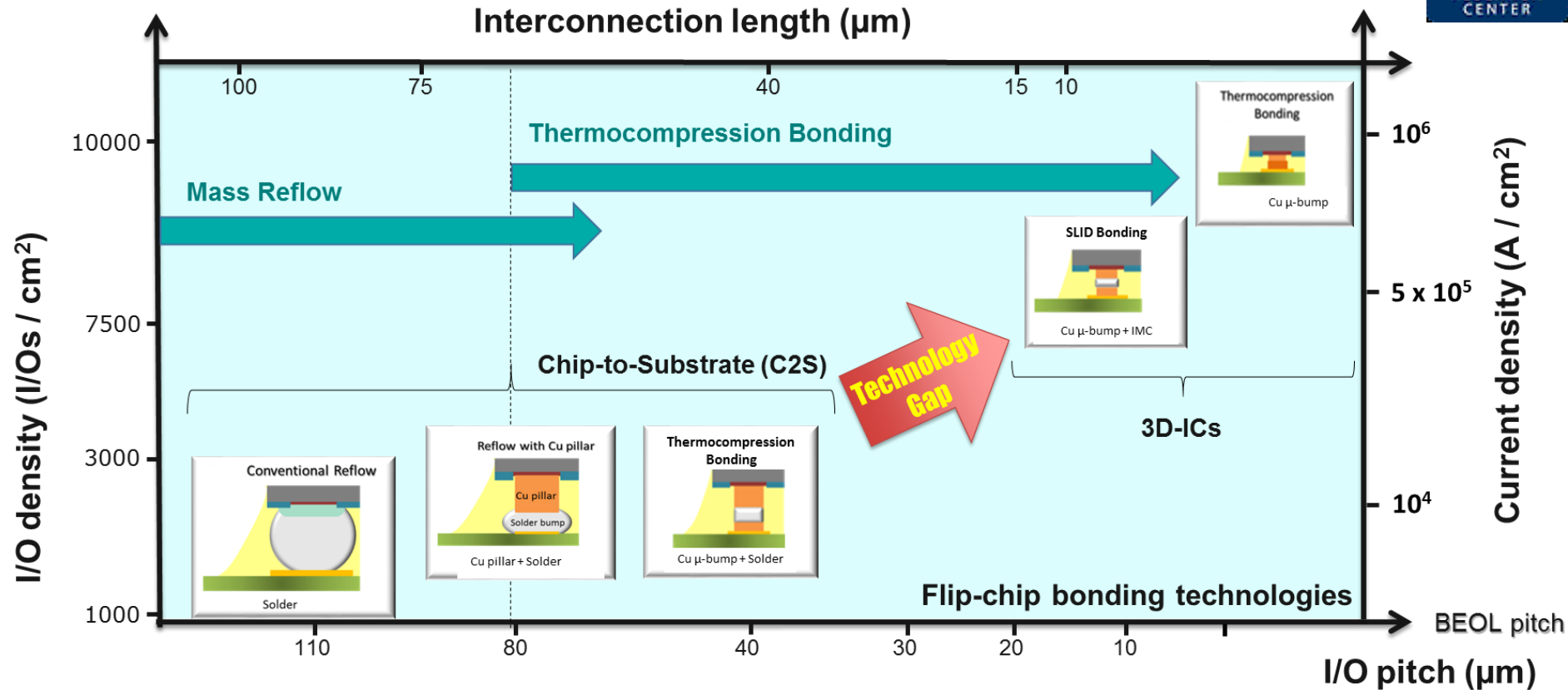


## Assembly bump characterization

- 35  $\mu\text{m}$  pitch, 20  $\mu\text{m}$  dia Cu-SnAg bumps

Courtesy: Siddharth Ravichandran, PRC  
Fuhan Liu, PRC

# Assembly....Closing the Gap



- ❑ Sn-based lead-free solders are reaching their limits in pitch scalability, power handling capability and creep resistance → **direct Cu-Cu bonding** as next interconnection node
- ❑ **Non-coplanarities** are a key bottleneck for development of a universal assembly solution

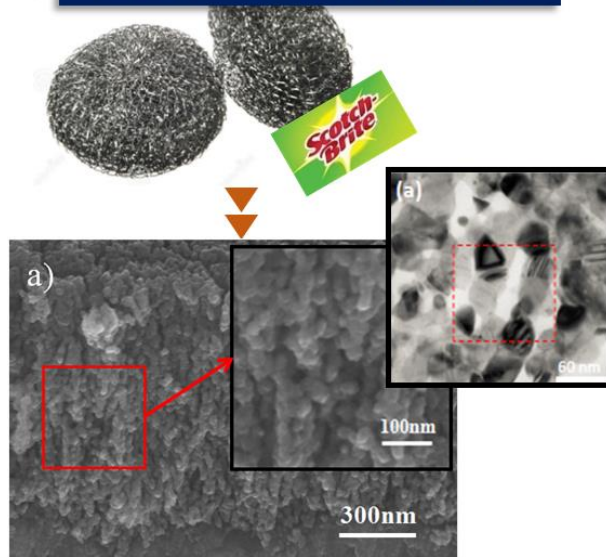


# Nanoporous-Cu Film Sintering

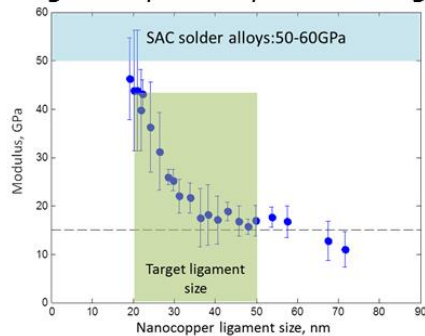
## Assembly Pitch < 20 $\mu\text{m}$



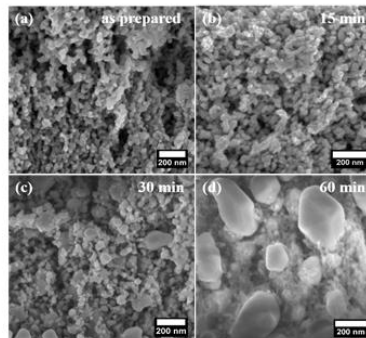
**Nanoporous (NP) Cu:  
nanoscale metal sponges**



*High compliance pre-sintering*

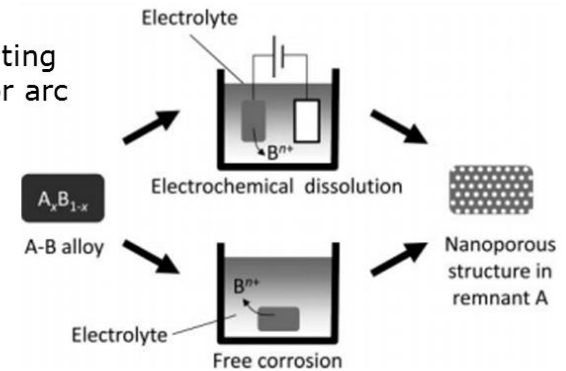


*Controlled densification*

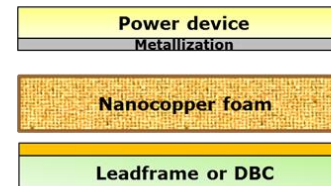


**Low-cost synthesis by selective etching**

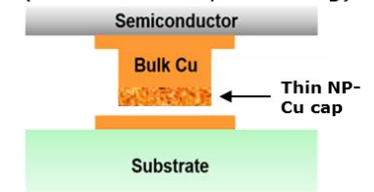
- Electroplating
- Furnace or arc melting



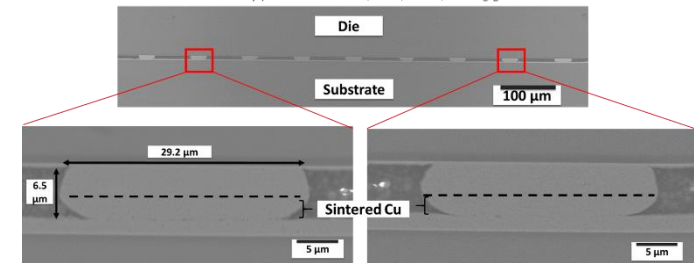
*Die-attach films, inserts or preforms*



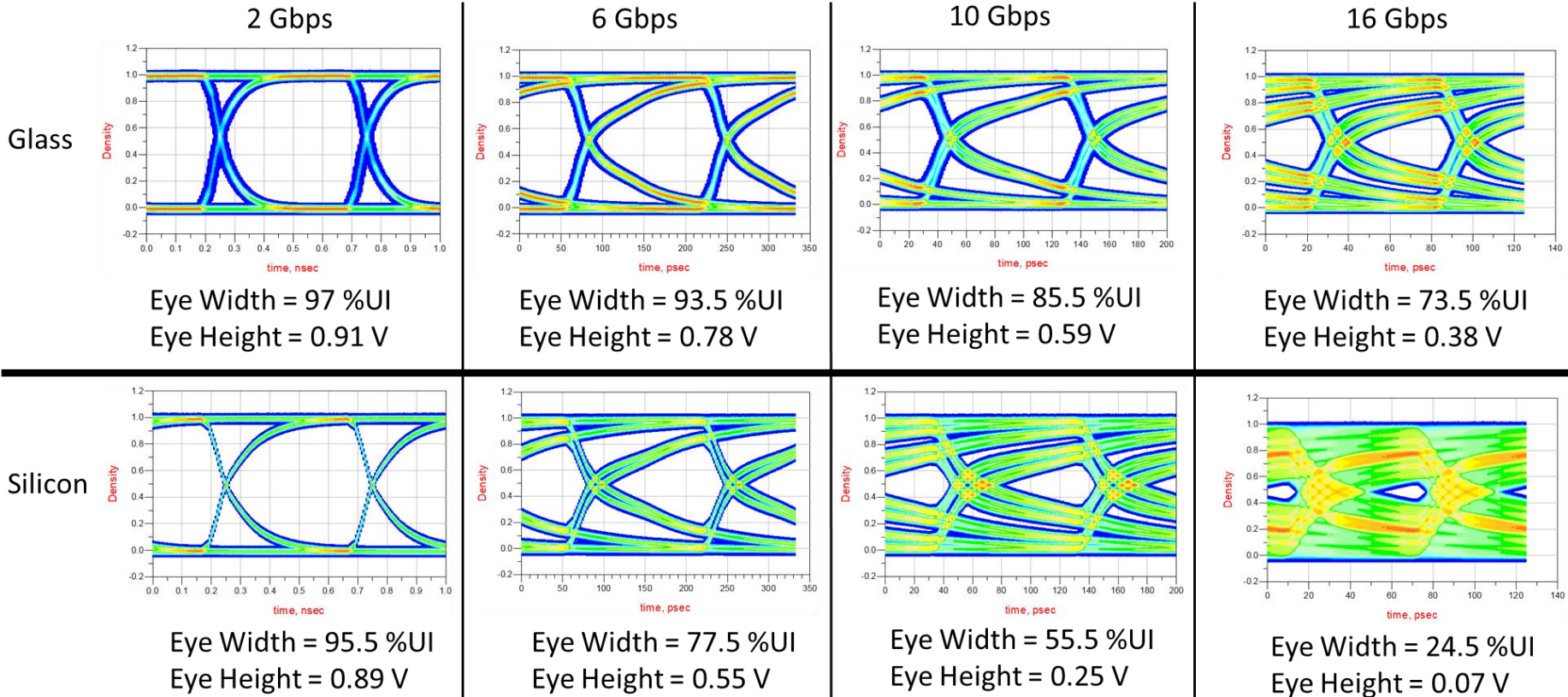
*Cu pillar with NP-Cu caps (semi-additive processing)*



Assembly parameters: 30MPa, 300C, 30min, forming gas



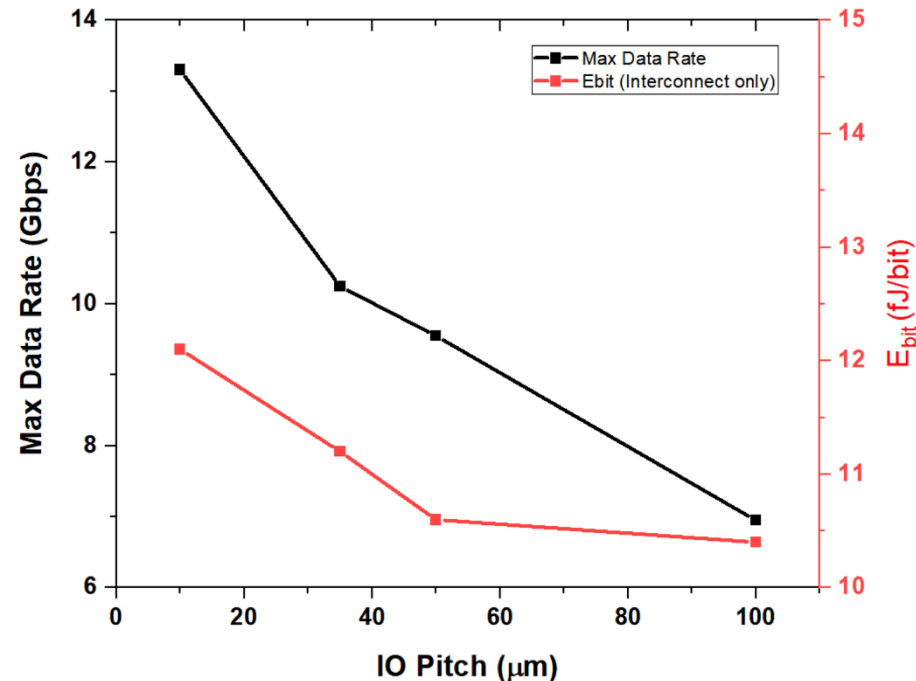
# Comparison of Glass & Silicon Interposer



Simulation settings:

- Statistical simulation at BER =  $1E-12$
- Rise/Fall Time = 10 %UI
- TX Impedance =  $50 \Omega$
- RX termination at  $\mu$ -bumps
- Channel length = 6 mm
- Bump Pitch/Diameter = 55/20  $\mu\text{m}$
- Line Width/Spacing/Thickness = 2  $\mu\text{m}$

# Energy Per Bit & Bandwidth Density



	3D IC w/ TSV [Zhang, et al. '18]	Monolithic 3D [Zhang, et al. '18]	3D GPE (35 μm Pitch)
Bandwidth density	1.76 Tbps/mm <sup>2</sup>	12.625 Tbps/mm <sup>*</sup>	4.65 Tbps/mm <sup>2</sup>
ESD capacitor	50fF	50fF	0.5 pF
E <sub>bit</sub> (no ESD)	76.2 fJ/bit	3.7 fJ/bit	11.2 fJ/bit
E <sub>bit</sub> (with ESD)	176.2 fJ/bit	135.1 fJ/bit	1.01 pJ/bit

GPE: Glass Panel Embedded

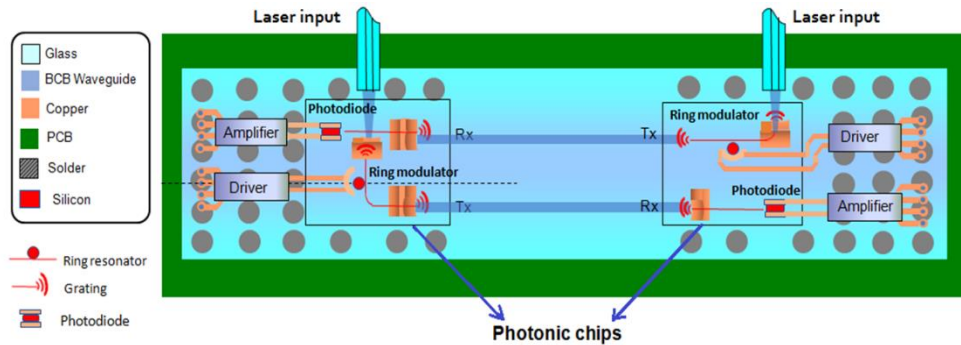
- ❑ E<sub>bit</sub> only includes interconnect. The ESD capacitances based on model assumptions add 1 pJ/bit
- ❑ E<sub>bit</sub> increases with decreasing pitch due to increased mutual capacitance between IOs



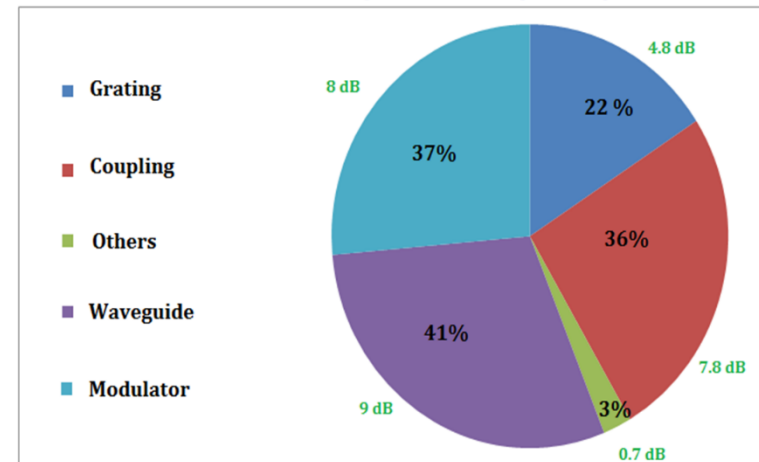
# Computing – Photonics Interconnects



- ❑ Fine Pitch Cu Interconnects too lossy
- ❑ Photonics in the Module
- ❑ Emerging Technology



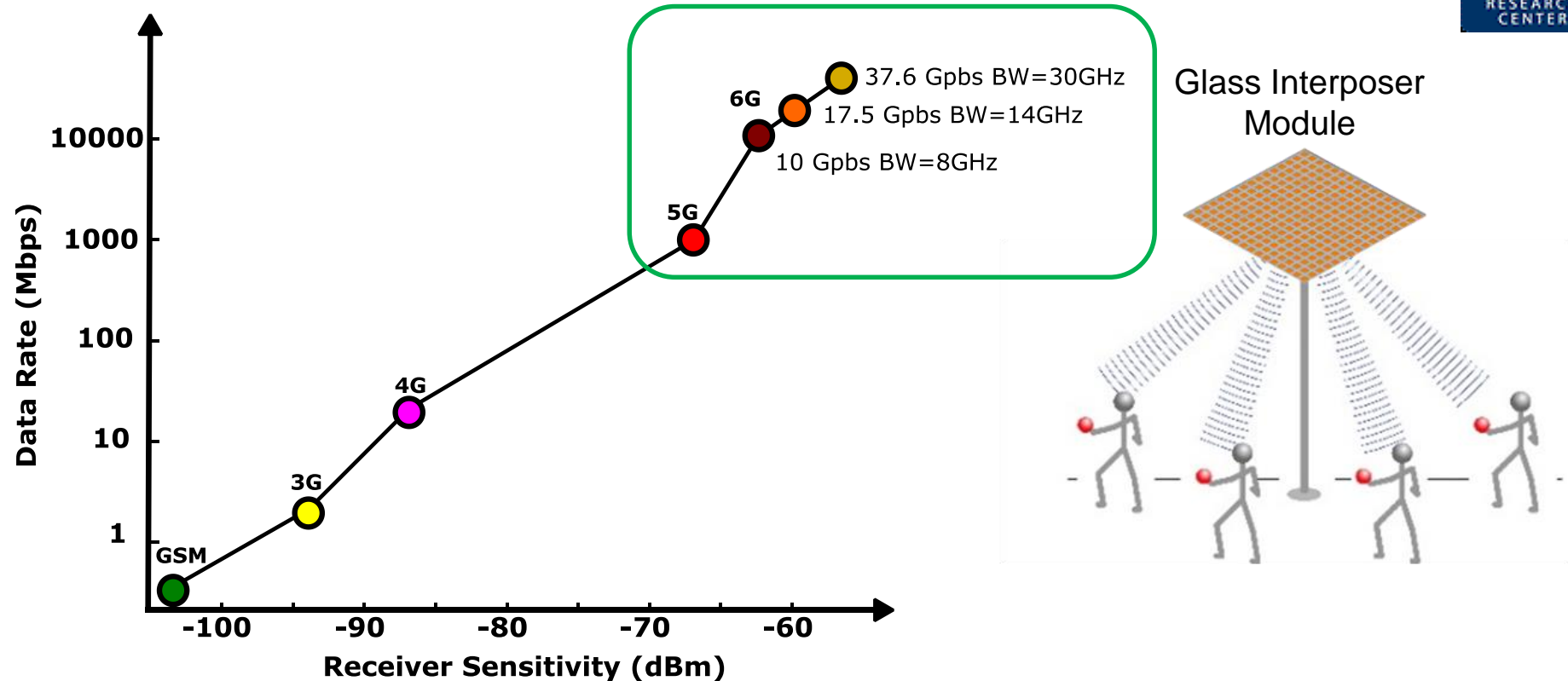
Interconnect Penalty for 50 mm (8x14G)



## Our (PRC) Focus

Metric	SERDES <sup>[5]</sup>	IBM Terabus <sup>[6]</sup>	Proposed work <sup>(estimated)</sup>
<i>Type of bus</i>	Electrical (Cu on FR4)	Optical (Silicone)	Optical (BCB)
<i>Energy consumption</i>	23.2 pJ/bit	4.65 pJ/bit	$\leq 1.2$ pJ/bit
<i>BER</i>	$10^{-9}$	$10^{-12}$	$10^{-12}$
<i>distance</i>	1 cm	36 cm	5 cm
<i>Data rate/lane</i>	40 Gb/s	160 Gb/s	896 Gb/s

# High Data Rate Wireless

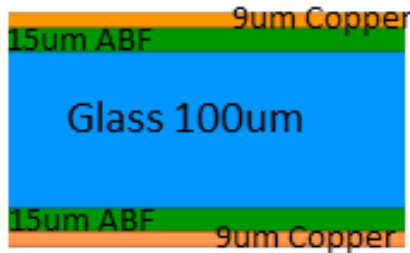


- ❑ Higher data rate requires larger bandwidth (1Gbps Vs 10Gbps)
- ❑ 5G and sub-THz (6G)
- ❑ Antenna in Package is essential

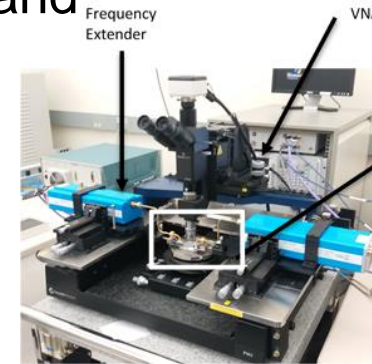
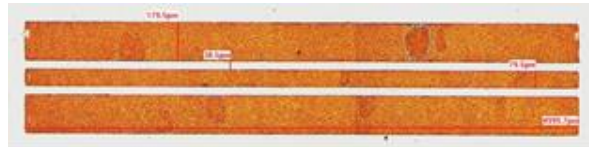
# Low Loss Interconnects



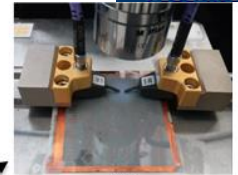
- Coplanar Waveguide (CPW) & Microstrip
- 0.2dB/mm@100GHz and 0.25dB/mm@140GHz**
- Comparable to LCP[2-3], Astra[4], Rogers [5] and Teflon[4]
- Microstrip: 0.076dB/mm (26-30GHz)



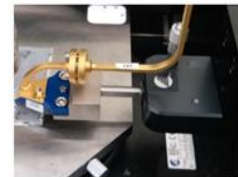
CPW Lines



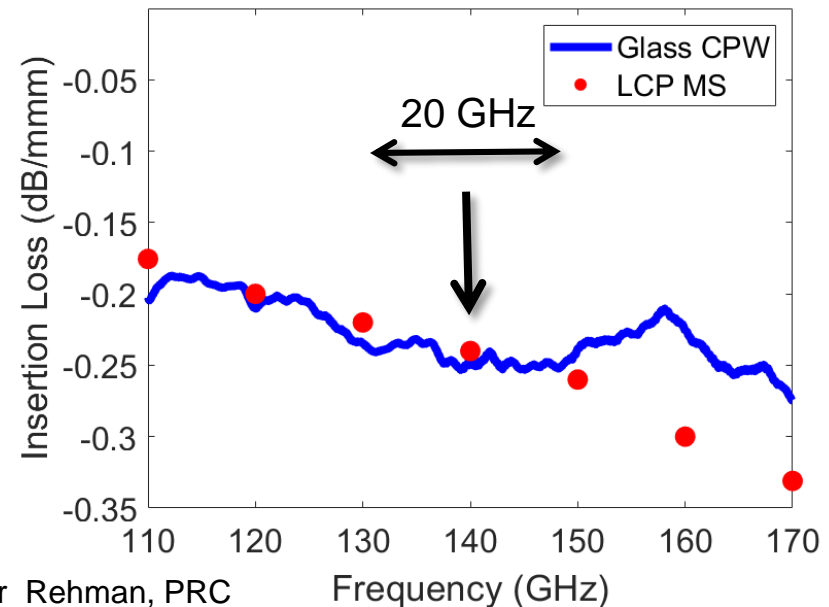
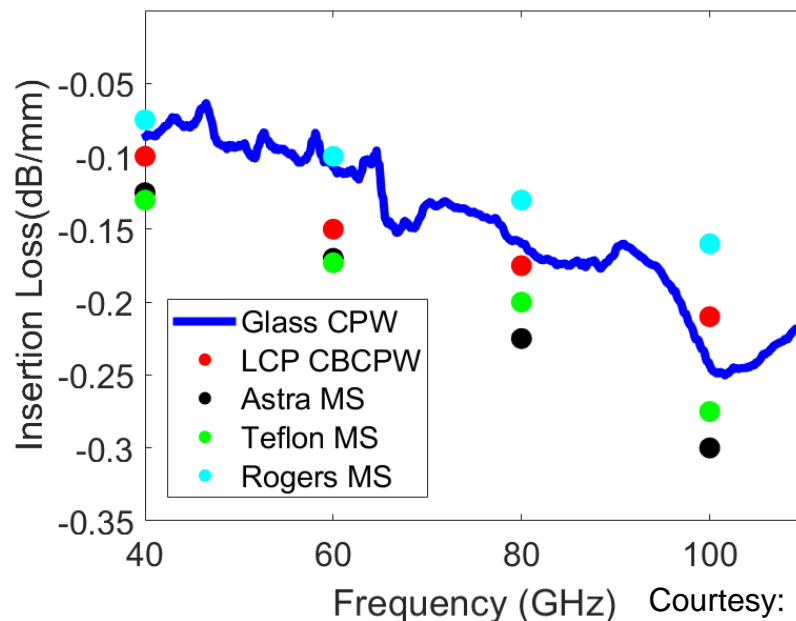
(a)



(b)



(c)



Courtesy: Mutee ur Rehman, PRC



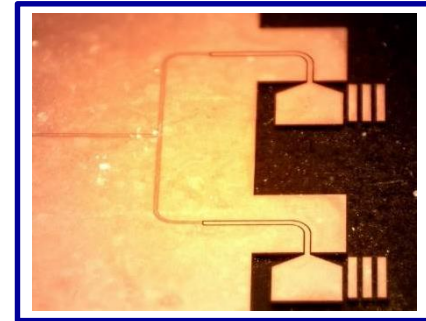
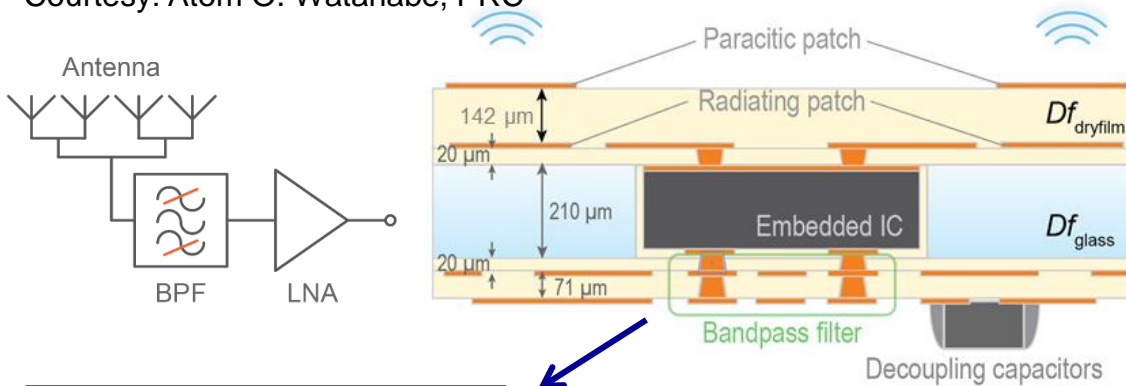
# Antenna in Package (AiP) – 5G



Module architecture

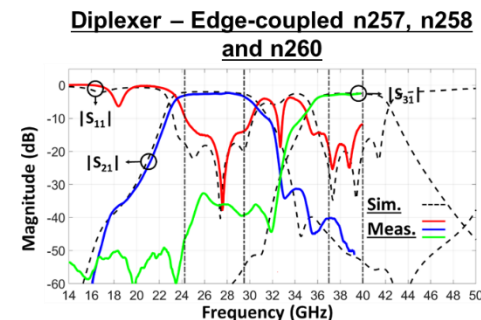
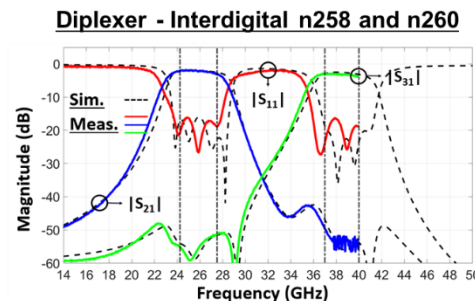
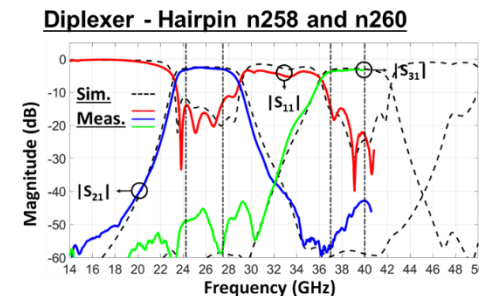
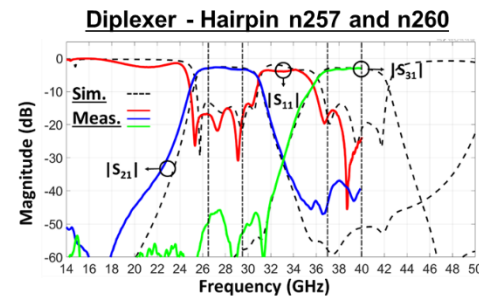
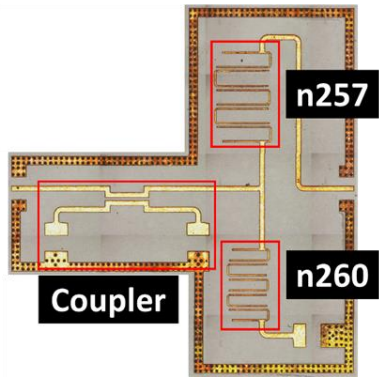
Module stack-up

Courtesy: Atom O. Watanabe, PRC



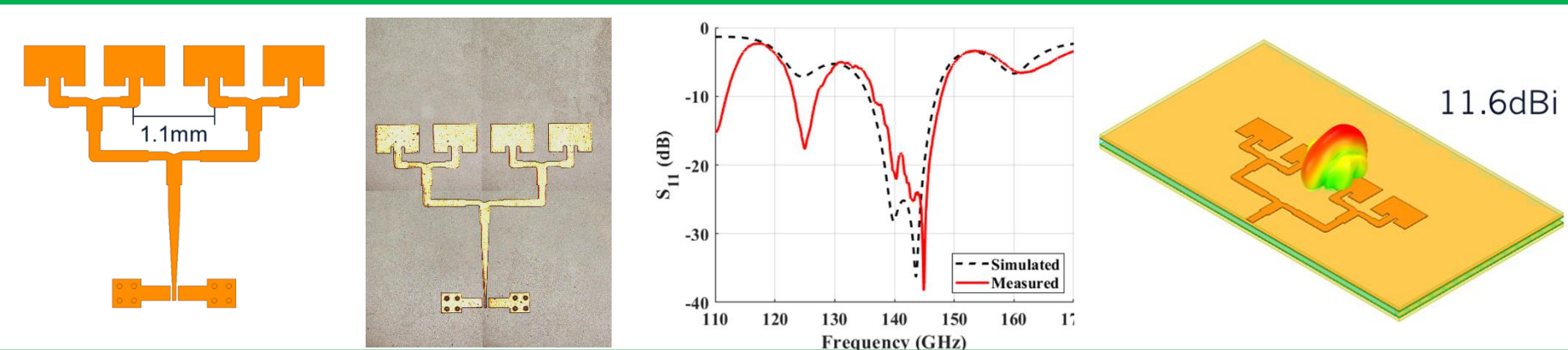
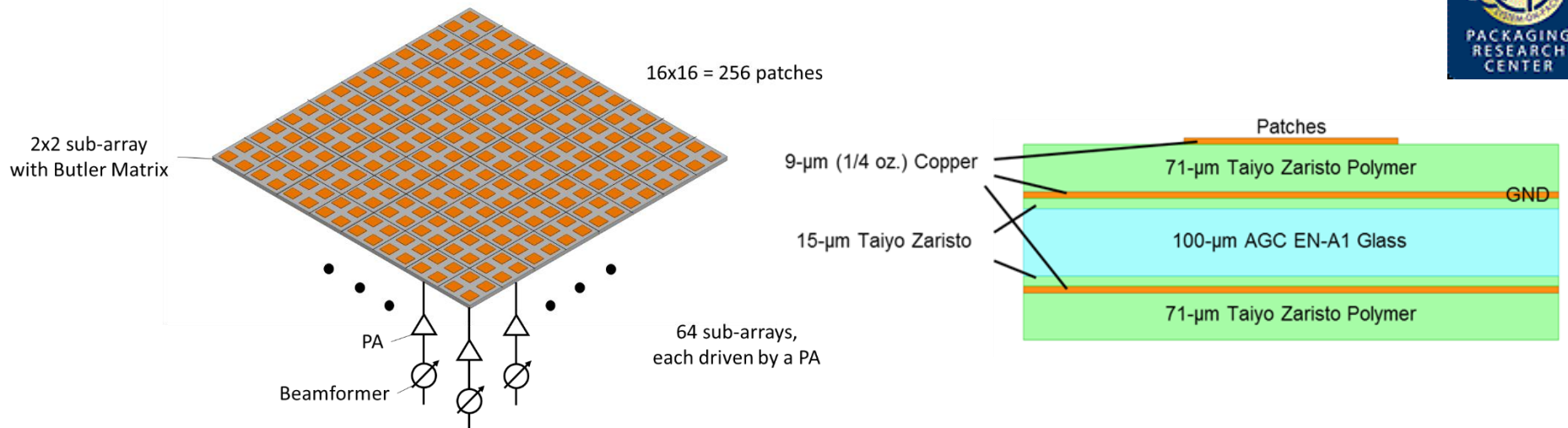
- ❑  $S_{11} < -9$  dB: 18.87 – 40 GHz
- ❑ Gain > 6.2 dBi: 24.25 – 40 GHz
- ❑ 5G bands: 24.25 – 40 GHz
- ❑ Good performance within the entire 5G bands

Integrated Hairpin Diplexer n257 and n260 & Coupled-line Coupler



Courtesy: Muhammad Ali, PRC

# Antenna in Package (AiP) – 6G



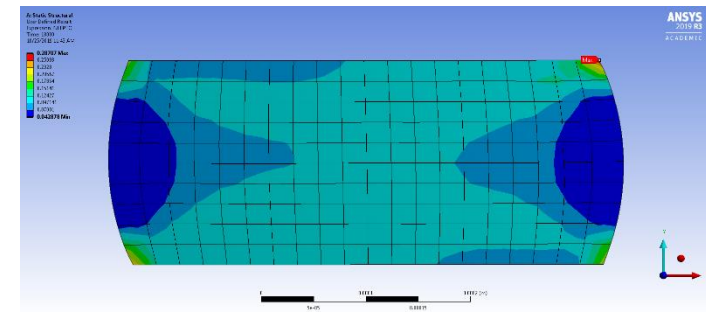
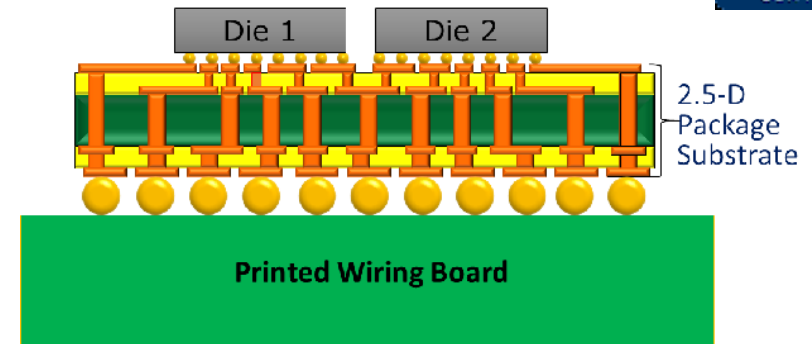
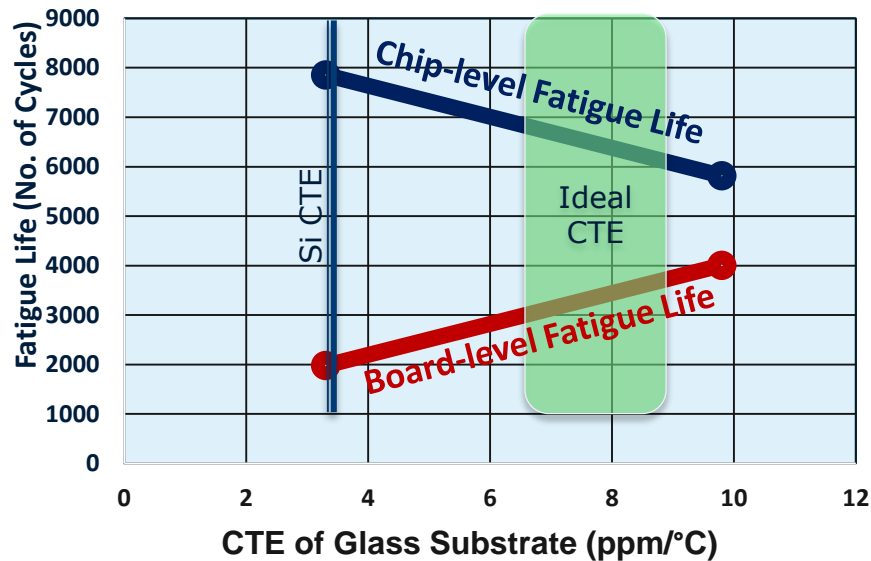
- ☐ 2x2 patch antenna elements - top layer
- ☐ 2-D Butler matrix - bottom layer
- ☐ Feed using vias
- ☐ Gain of each element: ~6dBi

- ☐ Element spacing: 1.1mm ( $\lambda/2$  @140GHz)
- ☐ 20% Bandwidth (goal)
- ☐ Total area: 3mm x 3mm

Kai-Qi Huang, GT-PRC.

# Reliability & Integration

Chip- and Board-level Reliability of Large Packages



Distribution of accumulated plastic strain in the second last solder ball for high CTE (9 ppm/K) glass substrate

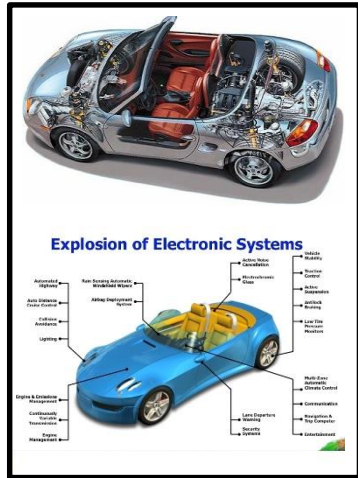
- ❑ Direct interposer assembly on to Printed Wiring Board
  - ❑ Tuned CTE for Glass Interposer maximizes Chip & Board reliability
- ❑ Eliminates ONE level of packaging



# Usage vs. Accelerated Testing Various Applications



AEROSPACE



AUTOMOTIVE



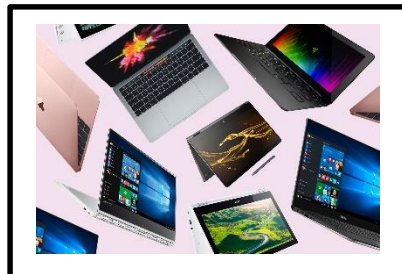
MILITARY

## 3D Systems Packaging Research Center

MEDICAL



COMPUTERS



COMMUNICATIONS



# Field Conditions—Aircraft Z

Operating Temperatures:



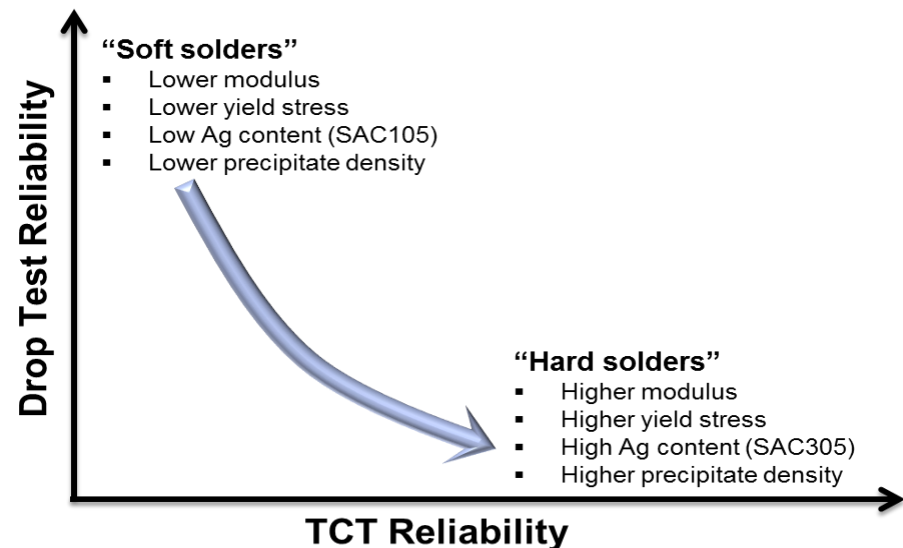
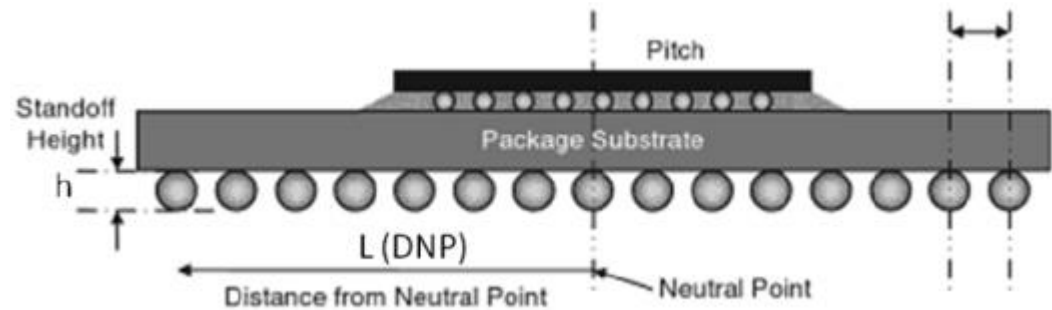
Case #	No. of Occurrences	T <sub>initial</sub> =T <sub>min</sub> , °C	T <sub>max</sub> , °C	T <sub>ave</sub> , °C	ΔT, °C
1	30	-55.0	85	15.0	140.0
2	60	-42.5	85	21.3	127.5
3	150	-32.5	85	26.3	117.5
4	155	-22.5	85	31.3	107.5
5	180	-12.5	85	36.3	97.50
6	950	-2.5	85	41.3	87.50
7	1700	7.5	85	46.3	77.50
8	1800	17.5	85	51.3	67.50
9	950	27.5	85	56.3	57.50
10	20	37.5	85	61.3	47.50
11	20	49.0	85	67.0	36.00

Case #	No. of Occurrences	T <sub>initial</sub> =T <sub>min</sub> , °C	T <sub>max</sub> , °C	T <sub>ave</sub> , °C	ΔT, °C
1	10	-55.0	-50.00	-52.25	5.00
2	20	-42.5	-31.0	-36.75	11.50
3	20	-32.5	-19.0	-25.75	13.50
4	20	-22.5	-7.00	-14.75	15.50
5	70	-12.5	5.00	-3.75	17.50
6	520	-2.5	15.5	6.50	18.00
7	950	7.5	25.5	16.50	18.00
8	1050	17.5	38.0	27.75	20.50
9	500	27.5	57.0	42.25	29.50
10	20	37.5	71.0	54.25	33.50
11	20	49.0	71.0	60.00	22.00

Diurnal Temperatures:

## Technical Challenges

- Aggravated solder strains
  - Large CTE mismatch
  - Large package sizes
  - Pitch reduction
  - Aggravated warpage
- Balanced fatigue & drop performance
- Additional constraints
  - SMT-compatibility
  - Reworkability
  - System-level reliability

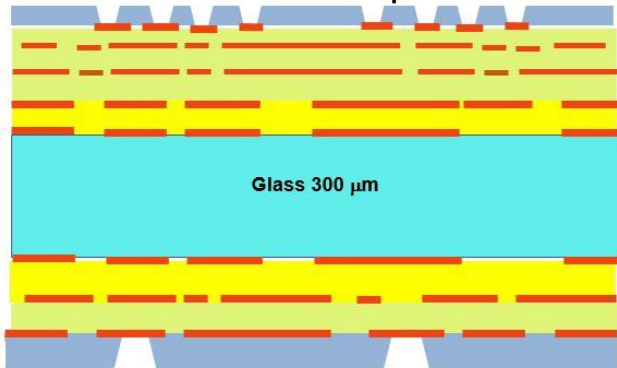




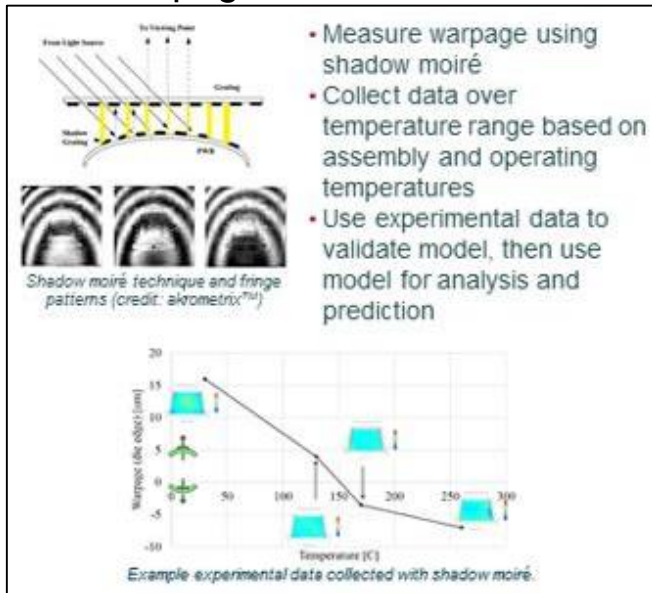


Prof. S. Sitaraman

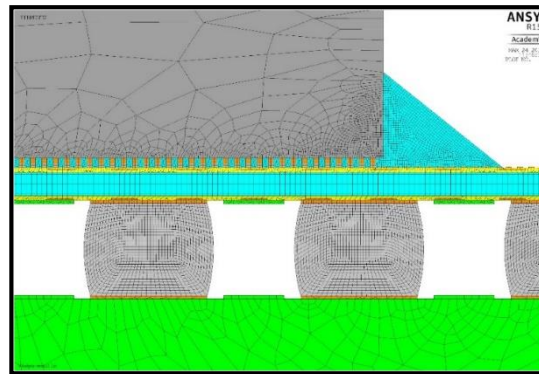
## Glass Interposer



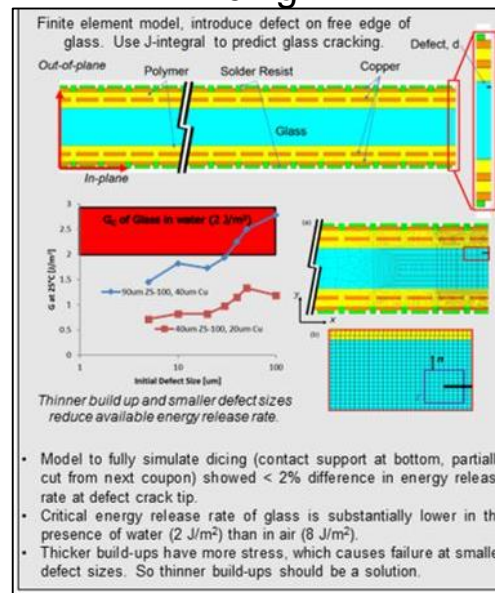
## Warpage Measurements



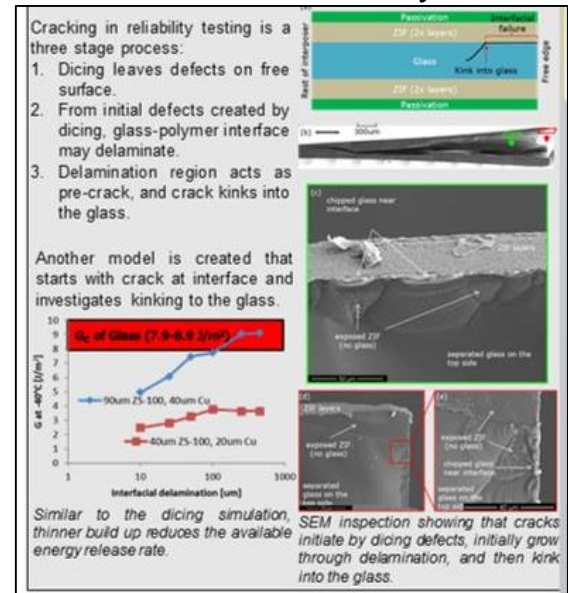
## Process Modeling &amp; Prediction from First Principles



## Dicing



## TCT Reliability





# Thank You



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